TECHNICAL SPEC FOR Wet processing system

System Model:
Akrion REARMOUNT

Wafer size:6inch

Application: etching

Process flow: HF, HNO3, NH4F, IPA, DIW

Front- or rear-mount: rear

Process Robot End-Effector:

Controller: control zone main components pneumatic solenoid panel, heated tank control unit, digital I/O boards (OPTO22)

Transfer robot: robot transfer arm, free standing unit

Common I/O Station: separate

Wafer transfer system: No

Dual buffer queues:

PFA Cassettes: yes

Configuration of each wet process modules:

Tank1: HF
Tank3: HNO3, HF and DI-water
Tank5: HF + NH4F
Tank7: HF
Vapor dryer: IPA

Pumps:

SECS: yes

Vintage:

Missing parts:

Defected parts:

Software: windows

Operating system: 386 computer/IAT

Photos to Collect

- All 4 sides
- Process modules
- Control panel
- Robots
- Loaders
- Chemical cannisters (close-up on chemicals)
- Gauges/Valves
- Exhaust pipes
- Pumps
- Inside all cabinets
- Serial plate
- Spare parts, manuals (if any)